

**IN THE U.S. PATENT AND TRADEMARK OFFICE**

In re application of

Yasuhiko KASAMA et al.

Conf. 9603

Application No. 10/585,245

Group 1792

Filed January 10, 2007

Examiner Marianne L. Padgett

ION IMPLANTATION SYSTEM AND ION IMPLANTATION SYSTEM

**INFORMATION DISCLOSURE STATEMENT**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

September 25, 2009

Sir:

In compliance with Rules 1.97 and 1.98, and in fulfillment of the duty of disclosure under Rule 1.56, the accompanying documents, copies of which are attached to this statement, are made of record on the enclosed Form PTO-1449.

A concise explanation of the relevance of these items is that these references were cited by the Korean Patent Office in the corresponding Korean Application filed July 9, 2007.

If necessary, the Commissioner is hereby authorized in this, concurrent, and future submissions, to charge any underpayment or credit any overpayment to Deposit Account

No. 25-0120 for any additional fees required under 37 C.F.R.  
§ 1.16 or under 37 C.F.R. § 1.17.

Respectfully submitted,

YOUNG & THOMPSON

/Robert J. Patch/  
Robert J. Patch, Reg. No. 17,355  
209 Madison Street, Suite 500  
Alexandria, VA 22314  
Telephone (703) 521-2297  
Telefax (703) 685-0573  
(703) 979-4709

RJP/gcg